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In re Application of:	)
David Thomas FORREST, et al.	)
International Application No. PCT/US2004/040629	) ) )
International Filing Date: 06 December 2004 (06.12.2)	) (2004))
U.S. Serial No.	)
U.S. Filing Date: 05 June 2006 (05.06.2006)	) )
For: FREE-STANDING SILICON CARBIDE ARTICLES FORMED BY CHEMICAL VAPOR DEPOSITION AND METHOD FOR THEIR MANUFACTURE	)
Mail Stop PCT Commissioner of Patents P. O. Box 1450 Alexandria, Virginia 22313-1450	Attorney Docket No. 52993/326894 Date: 05 June 2006

## PRELIMINARY AMENDMENT

Sir:

Kindly amend the above-identified patent application prior to examination.

Amendment to the Specification appear on page 2 of this paper.

A listing of all pending Claims begins on page 3 of this paper.

Remarks appear on page 8 of this paper.